# Monthly LabAdviser update: 28/8 2018

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| Updated Subject | Contributor | Link to the updated pages |
| **XRD SmartLab**  Equipment page for the Regaku SmartLab XRD has been made | **Kristian H. Rasmussen @danchip** | [Characterization/XRD](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Characterization/XRD) |
| **InP etching in the III-V ICP**  InP etch with Cl2/CH4/Ar made in 2013 | **Matthew Haines/Kresten Yvind @fotonik** | [III-V\_ICP/InP-InGaAsP-InGaAs#InP\_etch\_with\_Cl2.2FCH4.2FAr\_2013](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/III-V_ICP/InP-InGaAsP-InGaAs#InP_etch_with_Cl2.2FCH4.2FAr_2013) |
| **Ti and Cr as adhesion layers to Au**  Description of interaction of Ti and Cr adhesion layers with Au thin films for micro/nanofabrication applications | **Matteo Todeschini @danchip/CEN** | [Thin\_film\_deposition/Deposition\_of\_Gold/Adhesion\_layers](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Deposition_of_Gold/Adhesion_layers) |
| **Nova NanoSEM 600 (@CEN)**  Description of Transmission Kikuchi diffraction characterization technique and its use for the study of thin films in a wide range of temperatures | **Matteo Todeschini @danchip/CEN** | [LabAdviser/CEN/Nova NanoSEM 600/Transmission Kikuchi diffraction](LabAdviser/CEN/Nova%20NanoSEM%20600/Transmission%20Kikuchi%20diffraction) |
| **Ph.d. project for Matteo Todeschini**  Nanoscale characterization of ultra-thin metal films for nanofabrication application | **Matteo Todeschini @danchip/CEN** | [Technology\_Research/Nanoscale\_characterization\_of\_ultra-thin\_metal\_films\_for\_nanofabrication\_applications](http://labadviser.danchip.dtu.dk/index.php/LabAdviser/Technology_Research/Nanoscale_characterization_of_ultra-thin_metal_films_for_nanofabrication_applications) |
| **Thermal Evaporator**  Equipment page for the Thermal Evaporator | **Rebecca B. Ettlinger/Mikkel Mar**  **@danchip** | [Thin\_film\_deposition/thermalevaporator](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/thermalevaporator) |
| **E-beam Evaporator (Temescal)** | **Rebecca B. Ettlinger**  **@danchip** | [Thin\_film\_deposition/Temescal](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Thin_film_deposition/Temescal) |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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| |  | | --- | | **5. 3. 1.35) Manual for Developer: TMAH Manual**, ver 2.2 | | **5. 3. 1.33) Manual for Spin Coater: Manual All Purpose**, ver 2.3 | |  | | **5. 3. 7.02) Manual for Dektak 8**, ver 8.1 | |  | | **5. 3. 7.47) Manual for AFM Icon-PT**, ver 3.3 | |  | | **5. 3. 5.12) Manual for furnace computers for the A-, B-, C-, D- and E-stack furnaces**, ver 4 | |  | | **5. 3. 5.13) Manual for BCB Curing Oven**, ver 2.2 | |  | |  | | **5. 3. 7.27) Manual for Dektak XTA**, ver 5.1 | |  | |
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